



**SWTEST**

PROBE TODAY, FOR TOMORROW

**2024 CONFERENCE**

# Novel direct probe solution for opto-electronic wafer-level PIC testing

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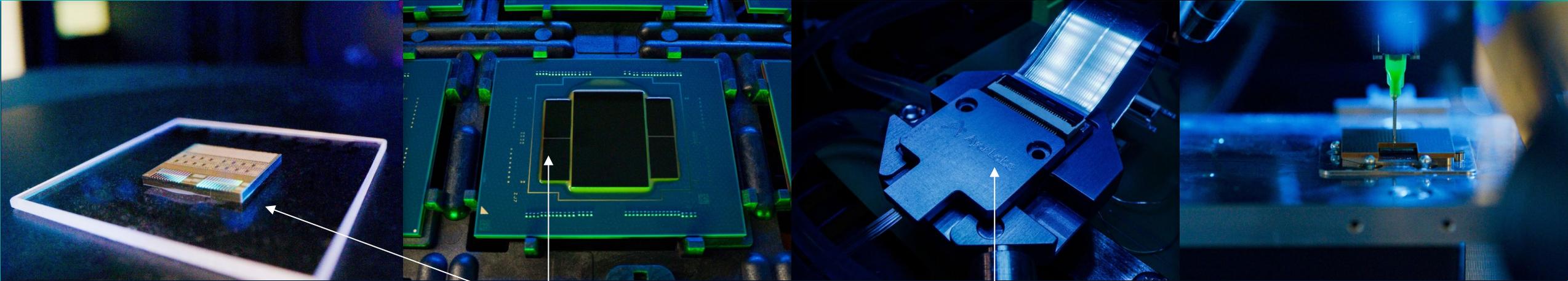


# Overview

- Introduction Ayar Labs
- Application (DUT for Photonic Test)
- Current Wafer Sort Flow
- Intended HVM Test Cell
- Technology Demonstrator
- Measurement Results
- Summary
- Outlook

# Introduction to Ayar Labs

We Design and Sell Optical I/O

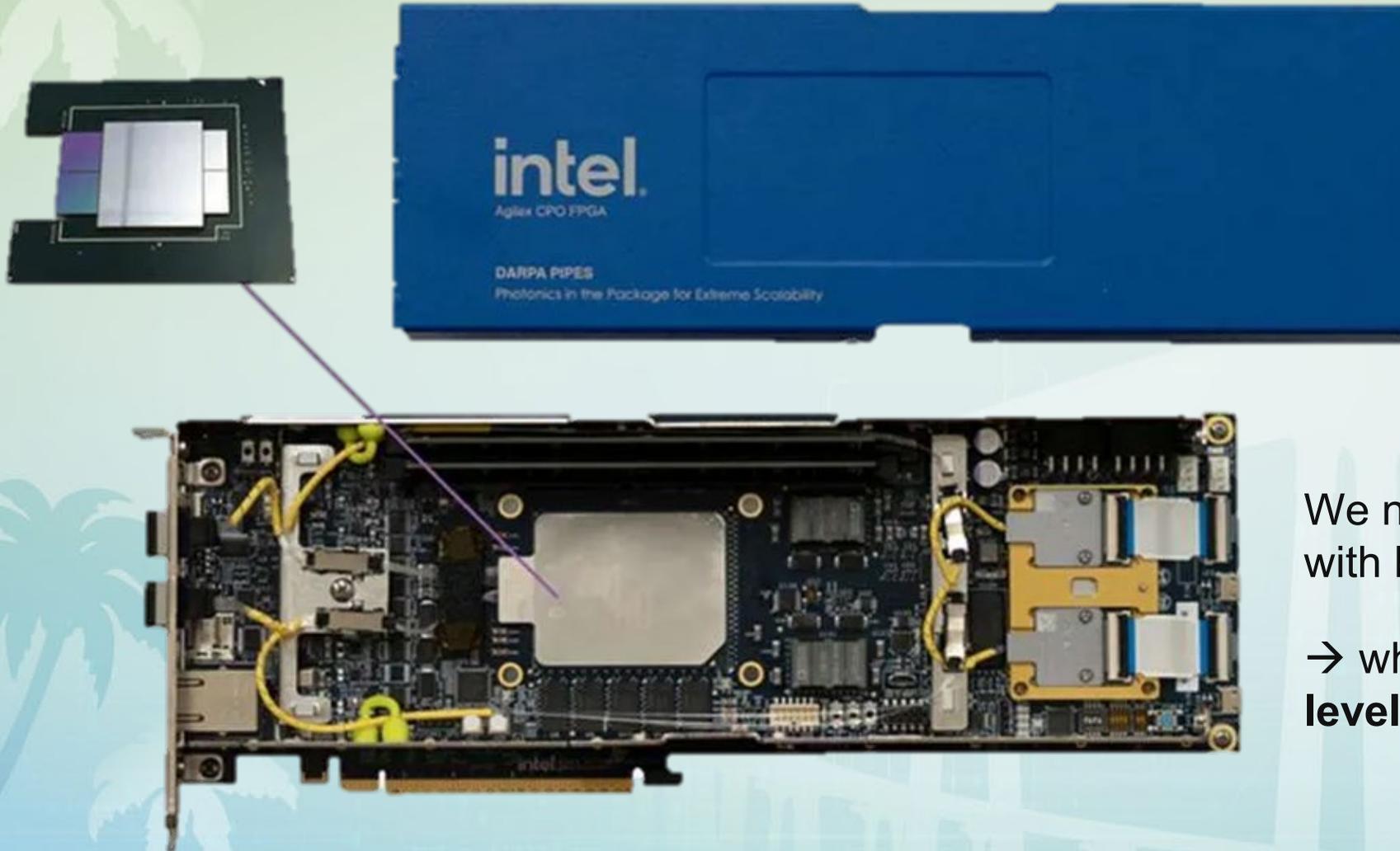


TeraPHY™ optical  
I/O chiplet

SuperNova™  
light source

Our solution is delivered as a CMOS based  
electronic/photonic chiplet using an external CW-WDM light  
source.

# TeraPHY Product

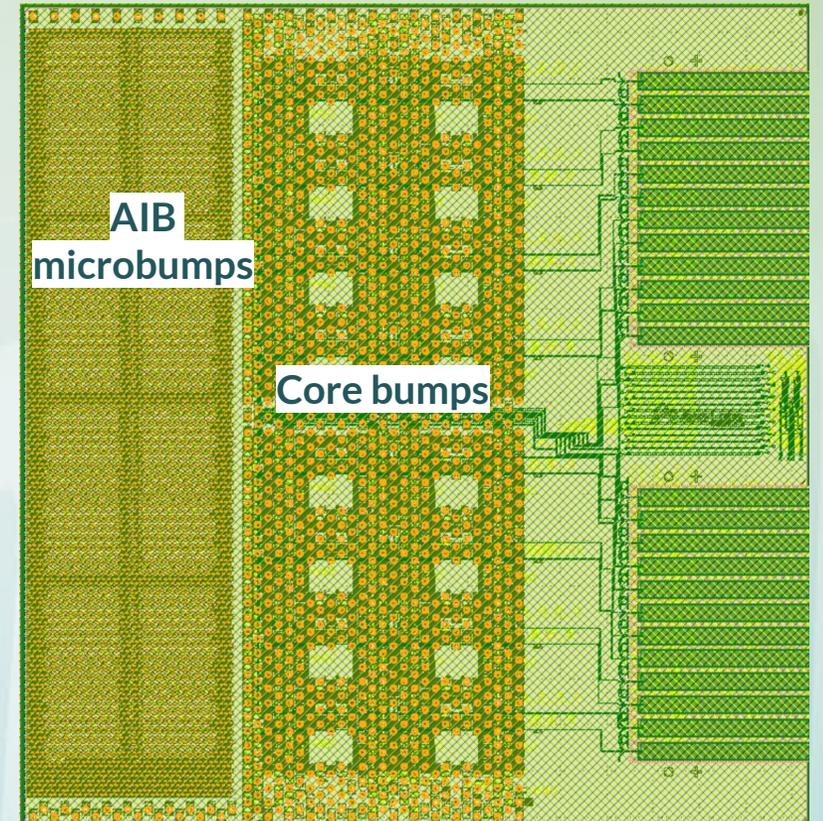


TeraPHY is an **optical I/O chiplet**, which our customers will co-package with their die (CPU, GPU, FPGA, etc)

We need to provide our customers with known-good-die (KGD),  
→ which means **extensive wafer-level screening.**

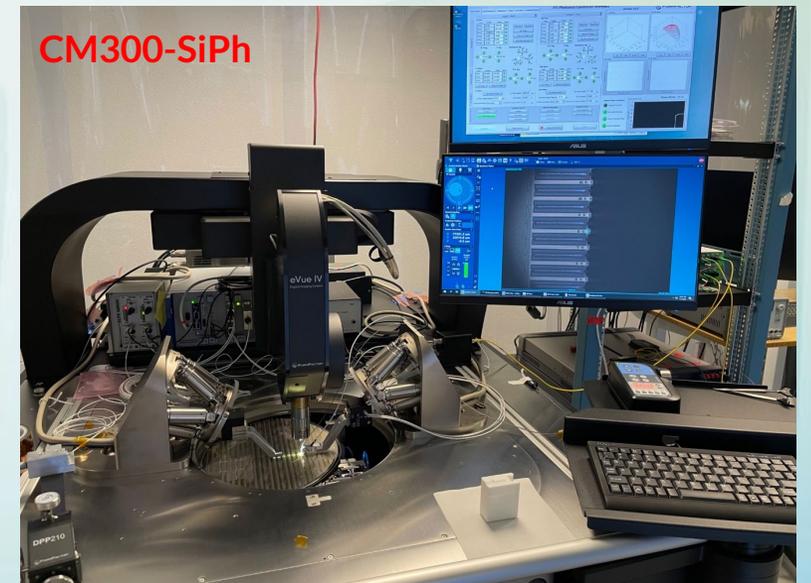
# Application (DUT for Photonic Test)

- Wide parallel interface (Advanced Interface Bus)
  - 4 Tbps bidirectional bandwidth
  - 8 transceivers (Laser, Tx, Rx)
  - 8 wavelengths per transceiver
  - 32 GBaud per wavelength
- Final test must be performed at wafer level to deliver known-good die (KGD)



# Wafer Sort

- Dual test insertion
- Electrical Wafer Sort (V93K ATE)
  - ~1400 bumps for electrical connectivity
  - Standby current, scan test, DFT, and at-speed functional test
- Optical Wafer Sort (CM300-SiPh probe station)
  - Optically couple into chip through edge couplers at wafer level
  - Passive optical characterization



# Wafer Sort

- **To meet cost targets, silicon photonics must use standardized equipment that can be shared across multiple customers**
  - Today, silicon photonics probe platforms and testers are customized to specific products
    - Test equipment must be consigned, or production run in house
  - Future: Convert Cap Ex into Op Ex by running test subcontractors
- **Drive to single test insertion on standardized platform for high volume manufacturing**
  - Test cell needs to provide both optical and electrical connectivity to DUT electro-optic final test

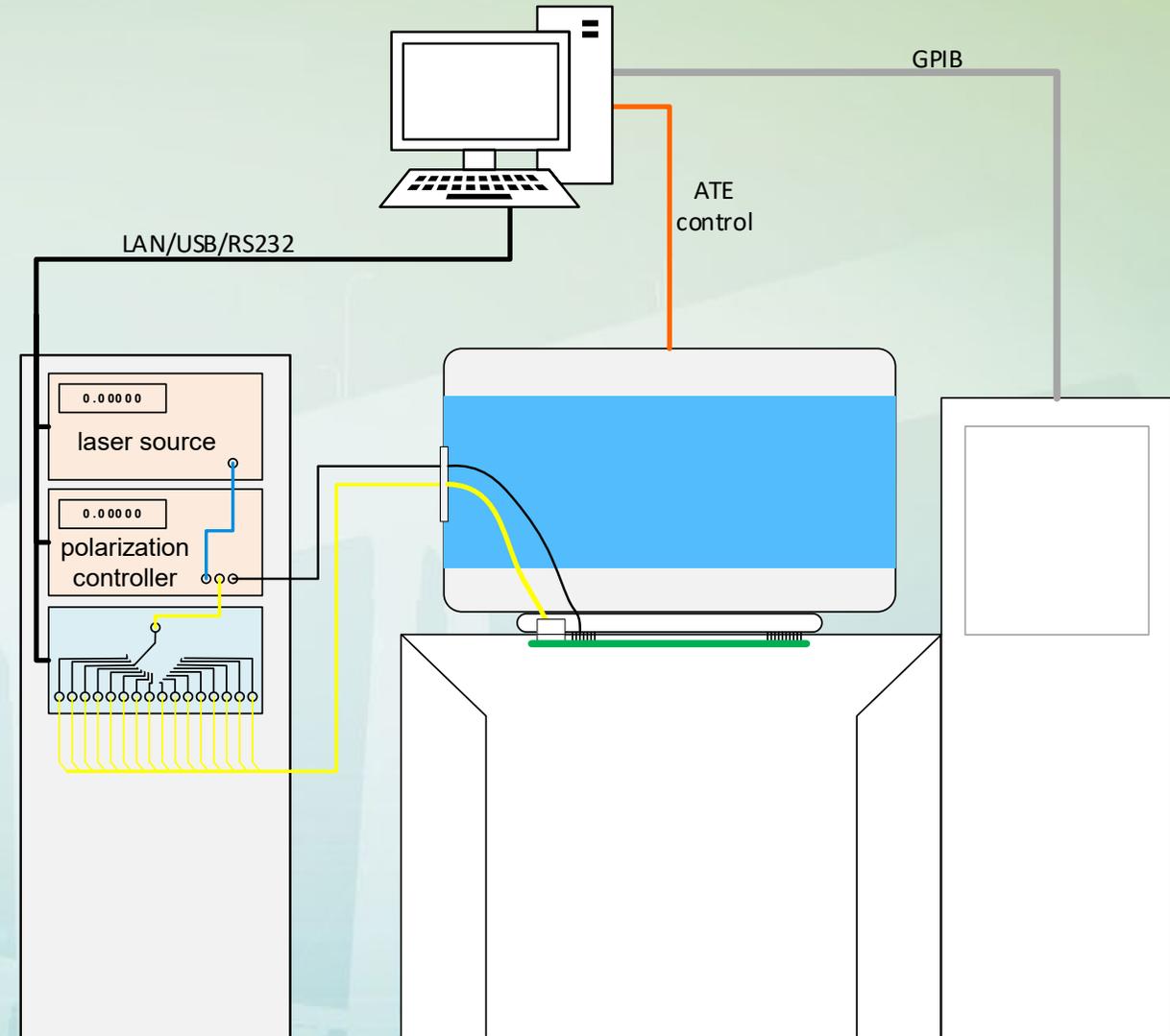
# HVM Test Cell

- Target HVM test cell

- As easy to set up as pure electrical wafer sort test cells
- Fully connected optical and electrical resources with docking test head to prober/probe card

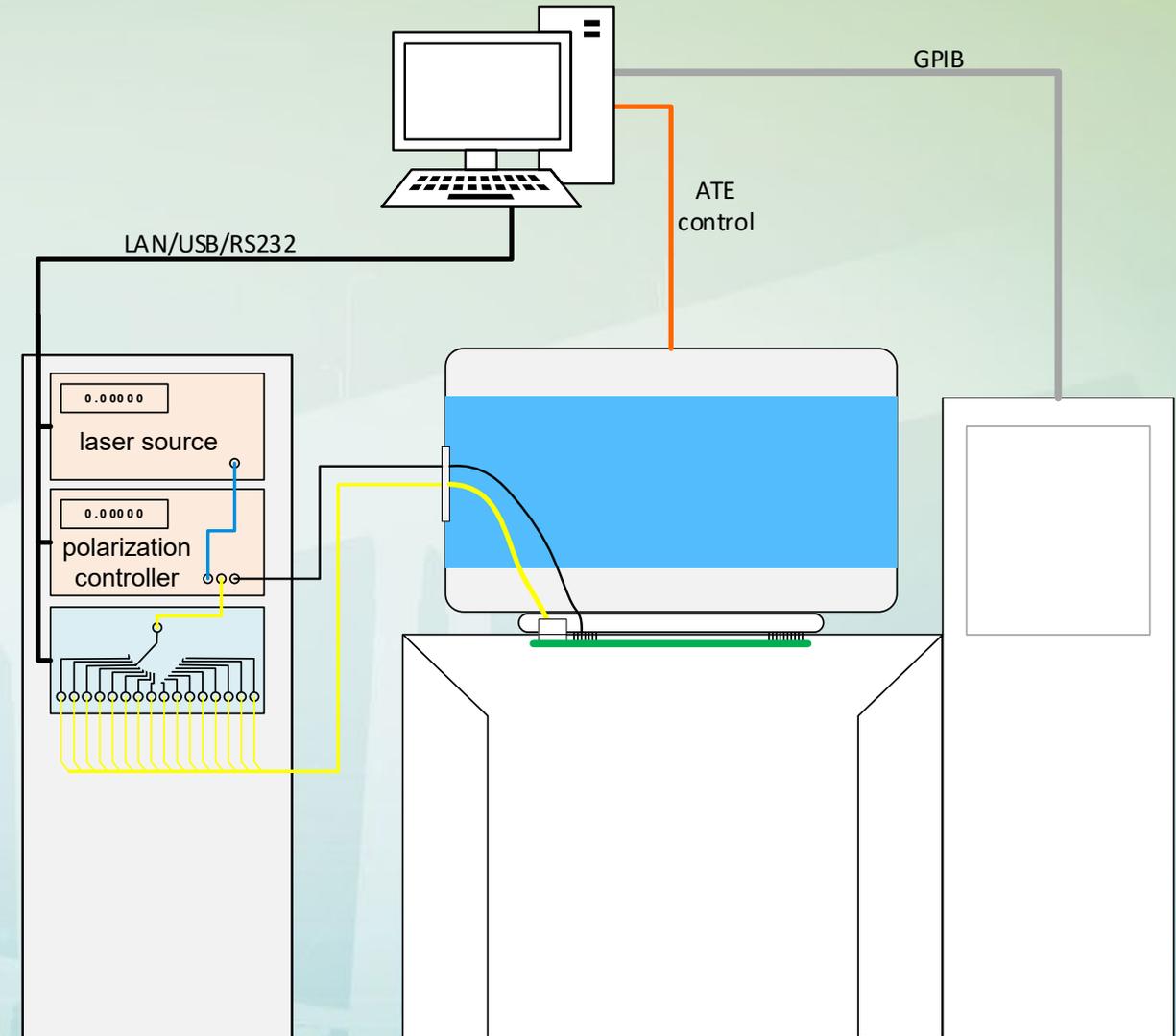
- Key building blocks

- Direct dock enabled UFO probe card
- Reliable and durable optical blind mate connection at DUT interface
- Test head side panel access to required optical and electrical rack resources



# Challenges towards HVM Test Cell

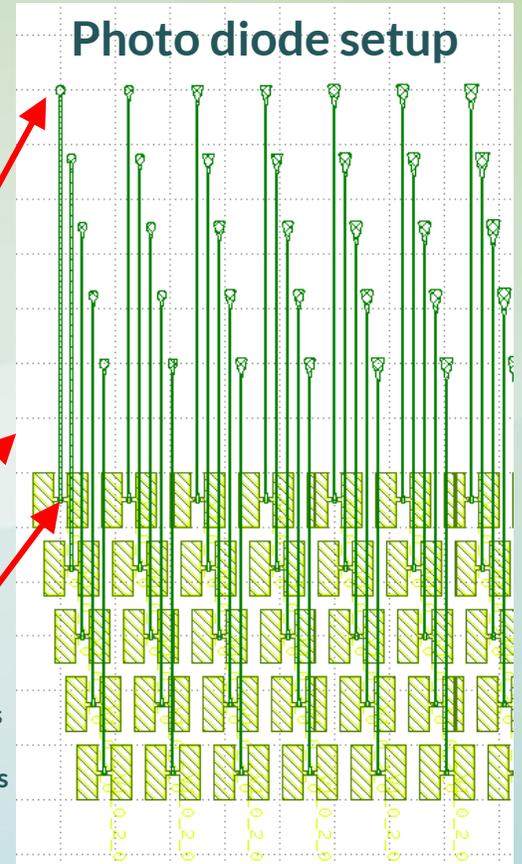
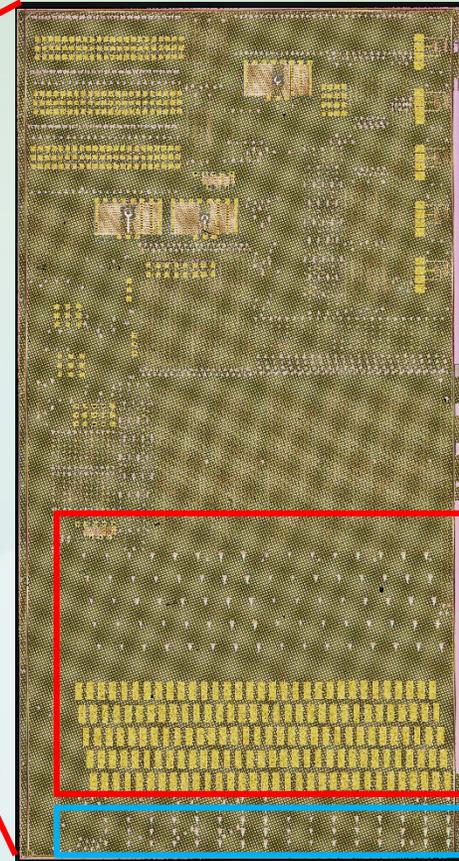
- Direct docking E/O probe card, especially for the optical docking
- Test cell integration into ATE Test Cell Control environment
  - Control of external instruments
  - Mechanical integration of additional E/O signal paths
  - Additional functionality for initial E/O alignments and setups
- Integration into an OSAT environment



# Test Device

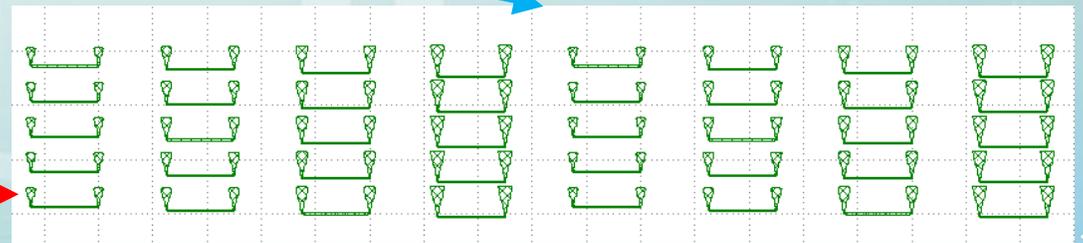
- Dedicated test die on the reticle
- Passive sites
  - 5 rows x 8 grating coupler loopbacks per row
  - Design of experiments to improve coupling loss to optical probe card
  - Measure wavelength dependent insertion loss
- Electro-optic sites
  - Grating coupler inputs to photodetector
  - Measure wavelength and power dependent photocurrent

3	6	9	13	16
2	4	<b>7</b>	12	15
1	5	8	11	14



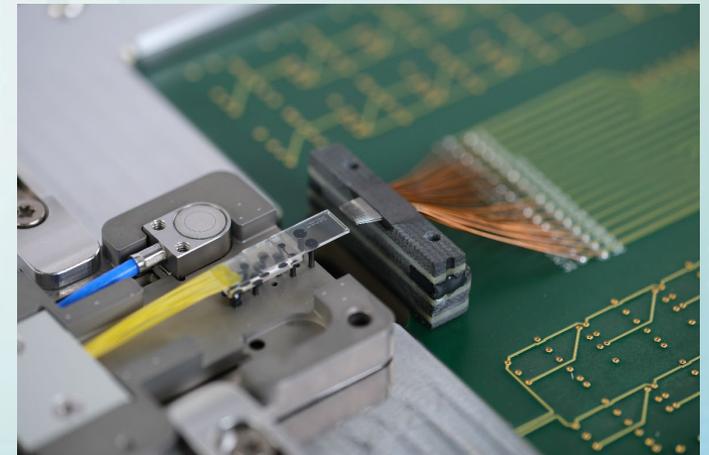
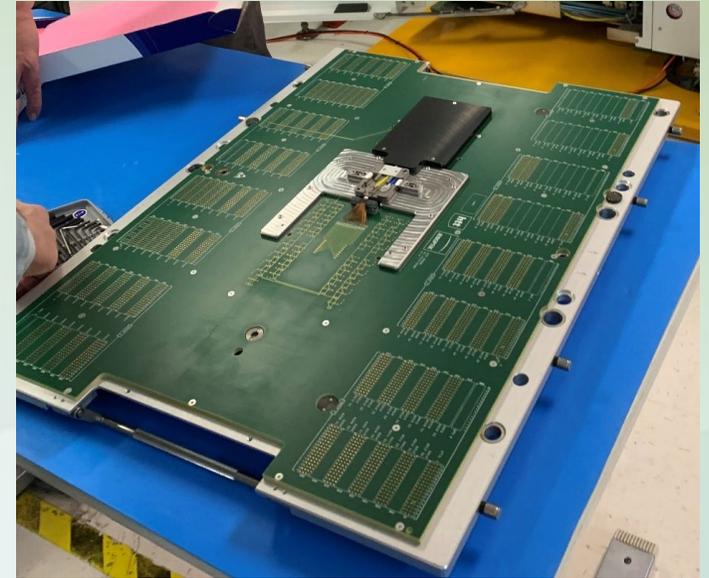
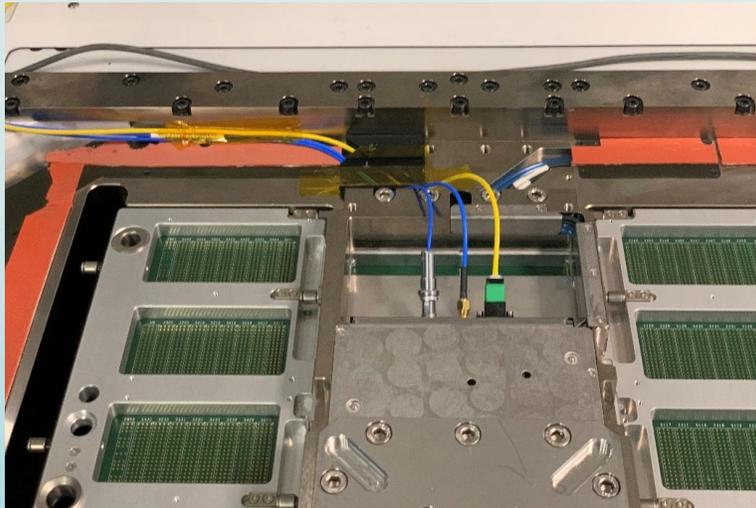
Loopback channel setup

Grating couplers



# Technology Demonstrator - Setup

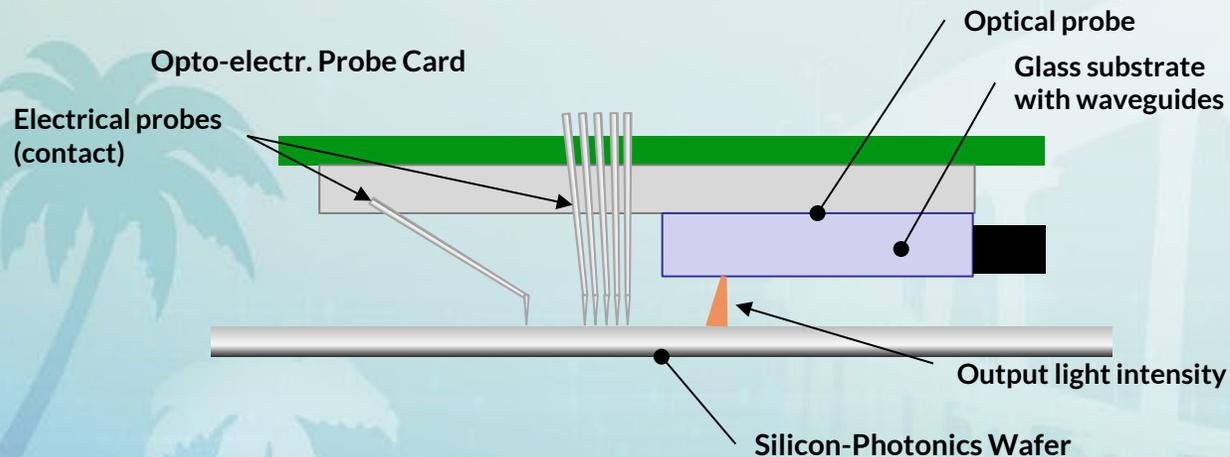
- Probe Card: UFO Probe™ TechDemo
  - Probe card format: V93000 direct docking
  - 32 cantilever needles (PD pads)
  - 16 channel optical probe head
  - Optical SM fiber connection with MPO connector
  - Capacitive distance sensor (CAP sensor)
  - Feedback loop to polarization controller



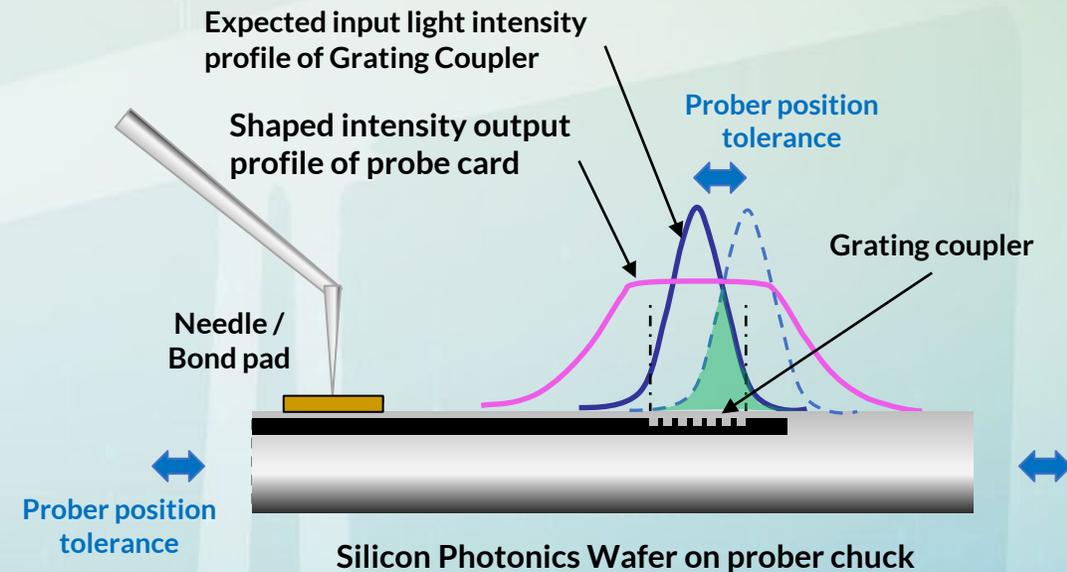
# Technology Demonstrator - Setup

- Probe Card: UFO Probe™ Working Principle

- Simultaneous optical and electrical probing in a single touch down
- Monolithic integrated optical module
- Alignment insensitive optical coupling for vertical emitting PICs
- Compensation of coarse prober position tolerances

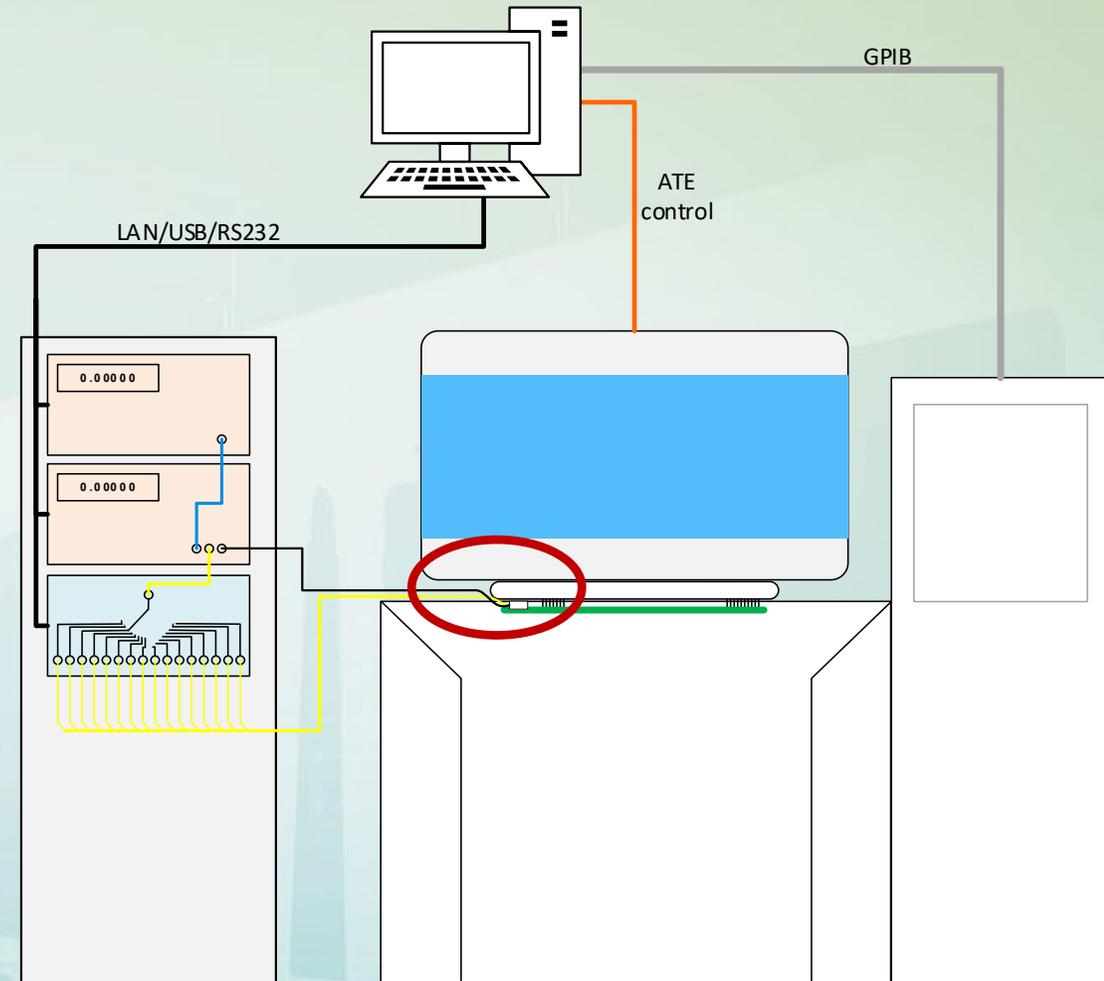


Optical concept compensates prober alignment tolerances.



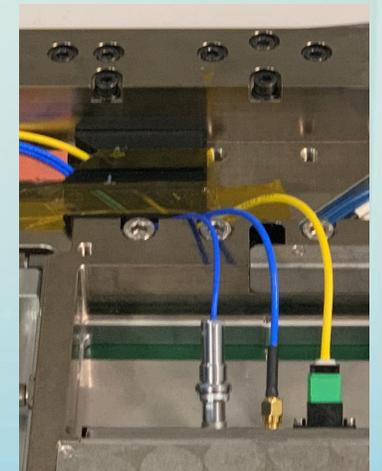
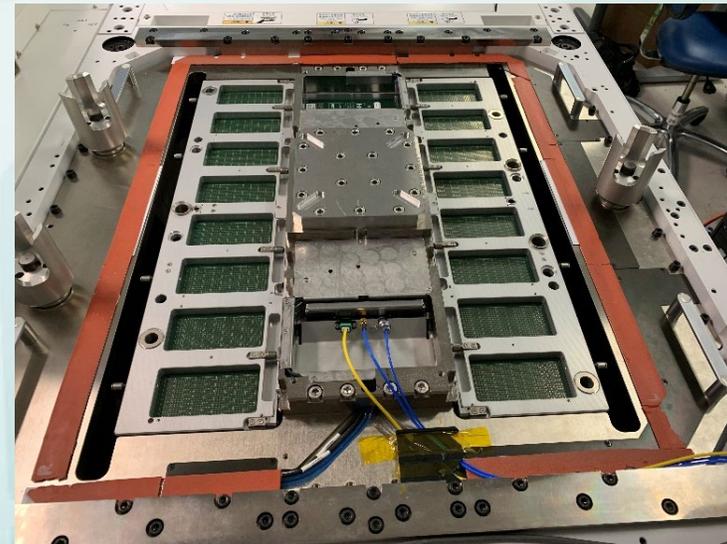
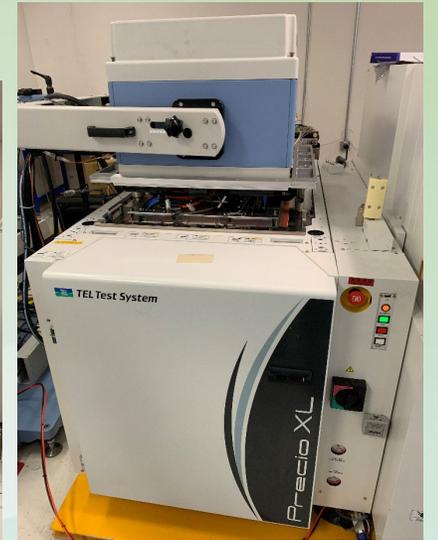
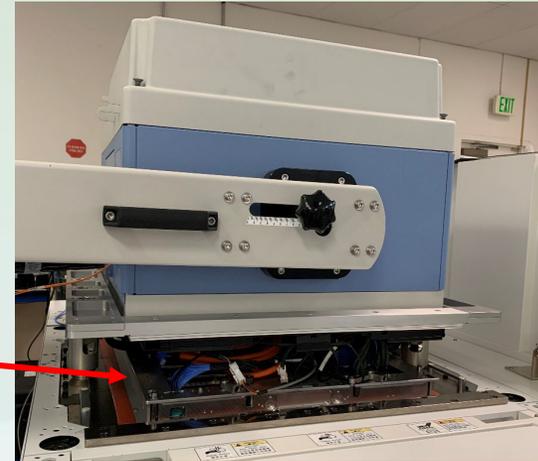
# Technology Demonstrator - Setup

- **Prober: Standard TEL Precio XL**
  - Prober control by ATE prober/handler driver via GPIB
- **Tester: Advantest V93000 SmartScale**
  - AVI 64 for photodiode current measurements
- **Optical Test Equipment (rack & stack):**
  - Santec TSL-570 tunable laser
  - Luna POS-203 Polarization controller
  - DiCon Fiberoptics MEMS 1x16 switch module
- **Probe Card: UFO Probe™ TechDemo**
  - V93K direct docking format
  - Cantilever needles and optical module
  - Microepsilon capacitive distance sensor



# Technology Demonstrator - Setup

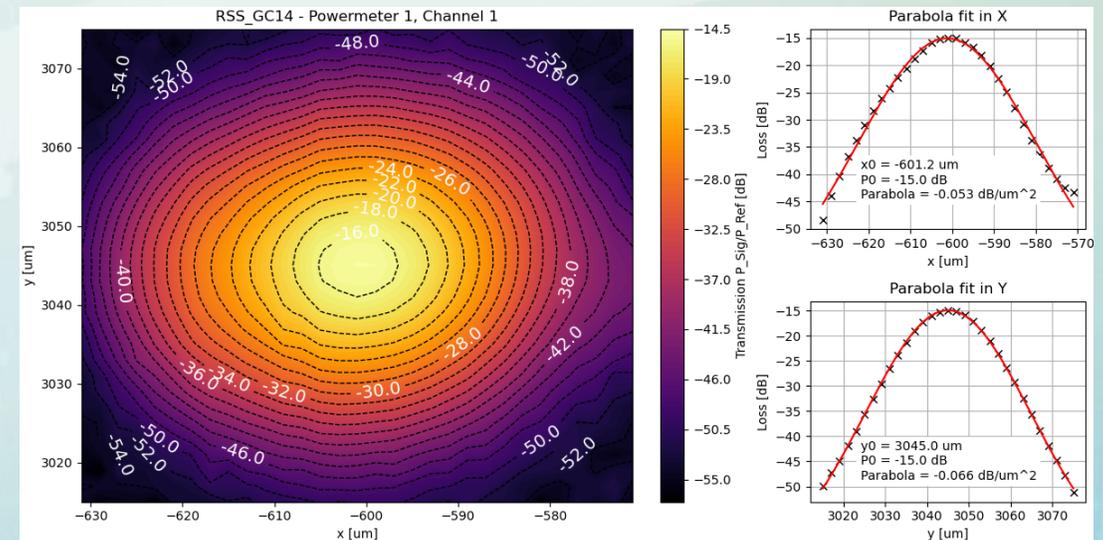
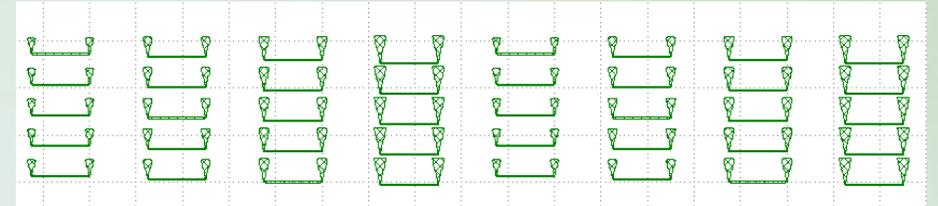
- **Prober: Standard TEL Precio XL**
  - Replaced sealing with 3D printed cable duct for optical and electrical cable access on docking plane (picture lower r.h.s)
- **Tester: Advantest V93000 SmartScale**
  - Top covers removed to reduce stress on optical and electrical cables when docking to prober
- **Probe Card: UFO Probe™ TechDemo**
  - Connector panel as separation plane for electrical and optical cables installed on probe card stiffener
  - After loading probe card, required connections were set up manually between rack and connector panel



# Measurement results

- Qualification of loop-back in Lab setup

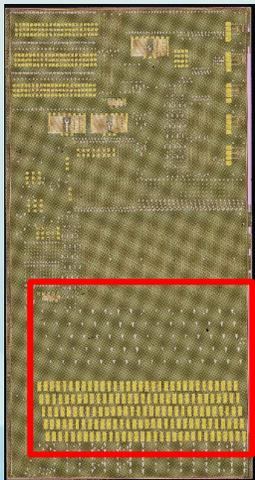
- Prior to prober measurements, the loop-back channel were qualified in a lab setup with same optical module
- No prober but a xy-scanning setup was used
- Entire loss of loop-back 15-17dB (including overfilling losses)



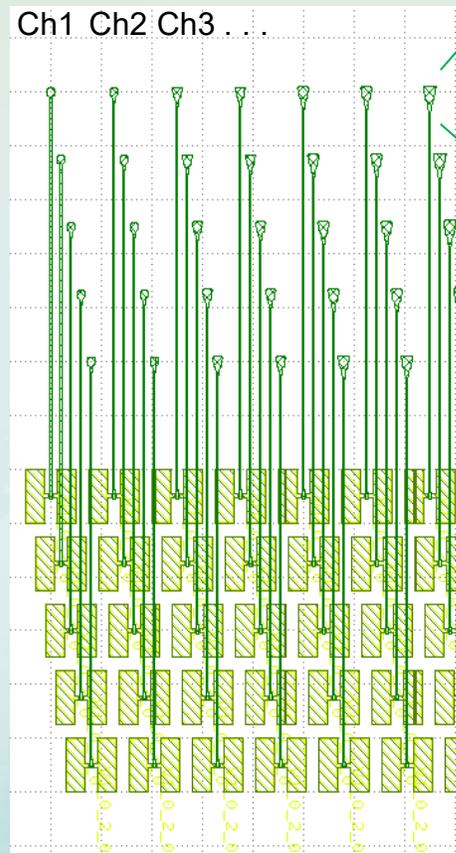
# Measurement results

- **Measurements at iTest**

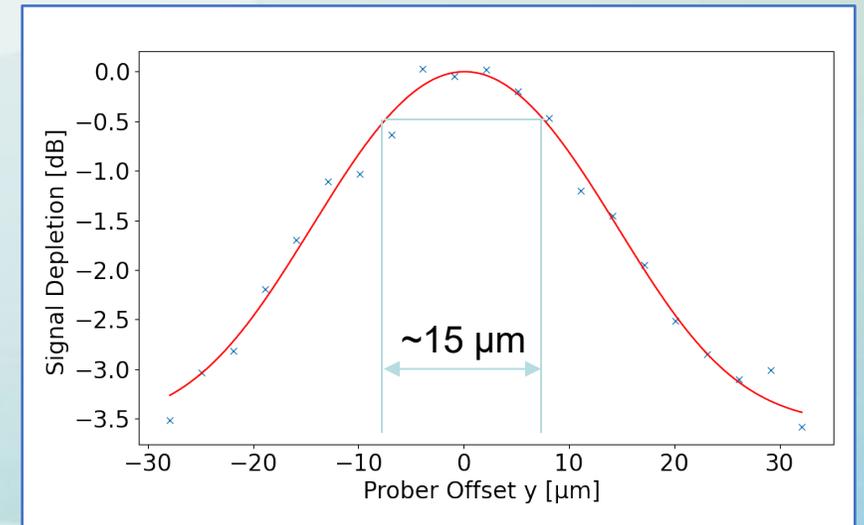
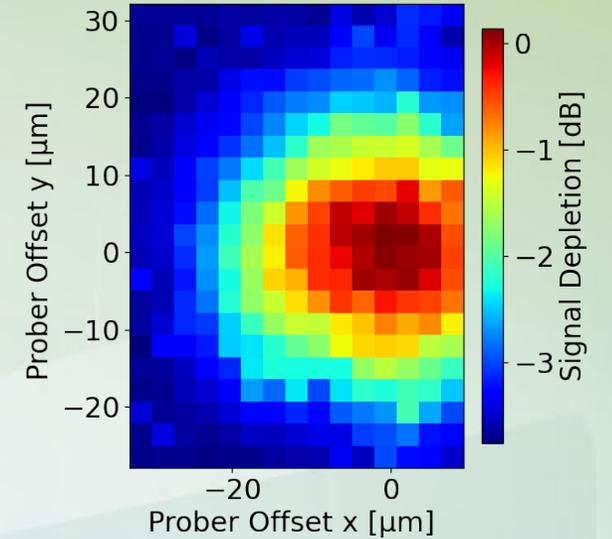
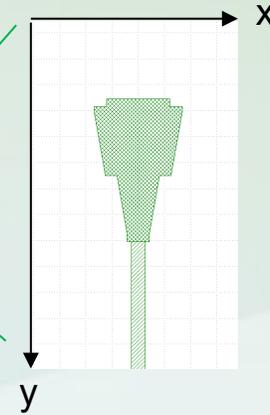
- Tolerance against alignment inaccuracies
- Prober positioning accuracy typ. 2 $\mu\text{m}$



Site 5  
Site 4  
Site 3  
Site 2  
Site 1



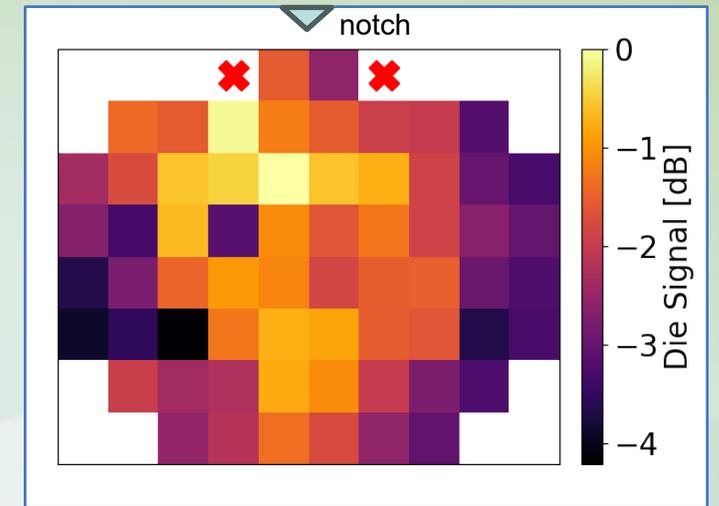
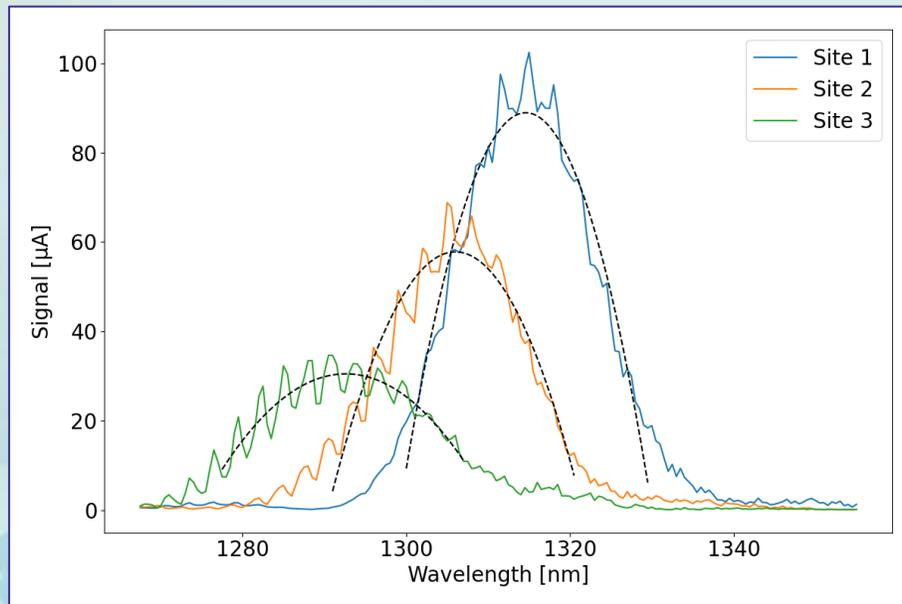
grating coupler



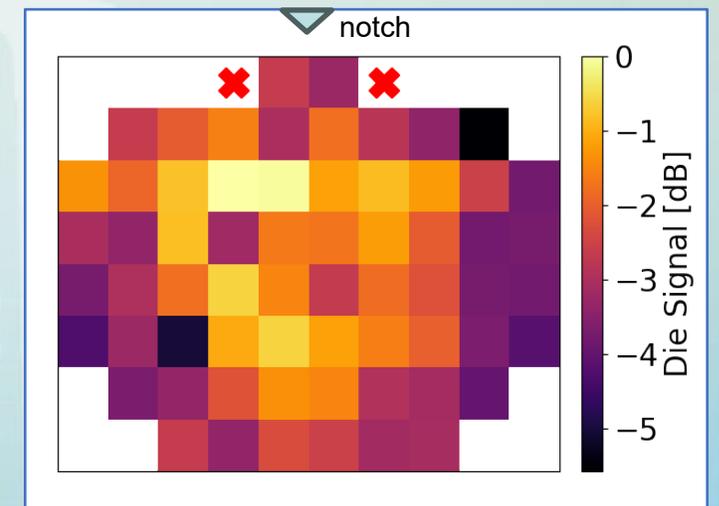
# Measurement results

- **Measurements at iTest**

- Wafer and site (sub-die) stepping without extra optical alignment per die
- Demonstrator setup allows characterization of chips
- Wavelength scan, maximum at site 1 (@ ~1316nm)



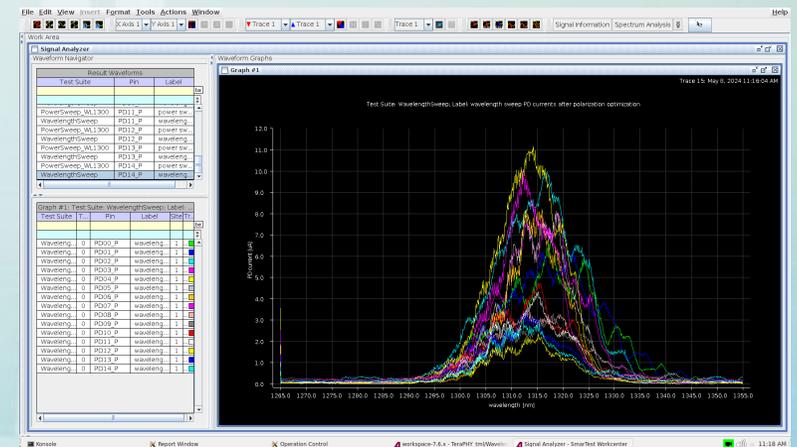
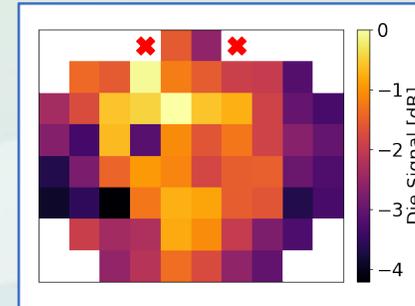
Wafer map channel 4



Wafer map channel 8

# Conclusion

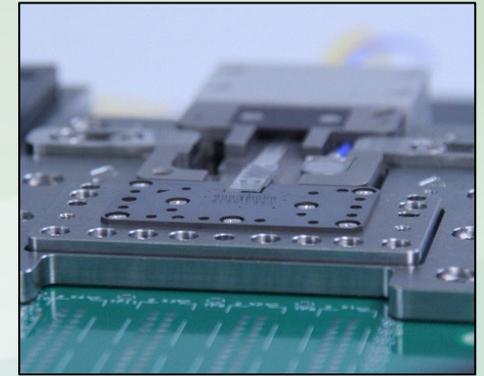
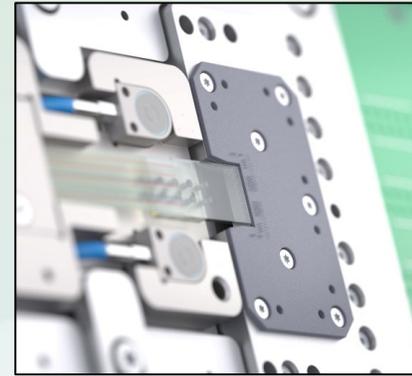
- We demonstrated
  - That a Standard IC Test Cell can test photonics
  - Direct prober loading of an E/O-probe card
  - Tester direct docking with an E/O-probe card
  - Tester/prober/external instrument handling
  - Initial lateral E/O-probe card alignment
  - Wafer and site (sub-Die) stepping
  - Wavelength scan



# Outlook

## Way to full HVM Test cell

- UFO Probe integration with Vertical Needles already demonstrated (UFO Probe™ Vertical)
- Next logical step: “full chip” direct docking probe card for V93000
- Direct and automated optical docking of E/O Probe Card to tester → ‘blind mate’ connection
- Optical channel routing through tester
- Automated probe card initialization routines by tester



# Acknowledgements

- **UFO Probe Team in Jena (Jenoptik)**
- **Clemens Leichtle (Advantest)**
- **Dries Vercruysse (Ayar Labs)**
- **Rabbi Islam, Timothy Truong, Philip Lu (iTest)**